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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: UNASSIGNED
MASAYA OGURA, ET AL.)
: Group Art Unit: 1756
Application No.: 09/811,419)
:
Filed: March 20, 2001)
:
For: EXPOSURE APPARATUS,) June 25, 2001
METHOD OF MANUFACTURING:)
SEMICONDUCTOR DEVICES)
AND PLANT THEREOF)

Commissioner for Patents
Washington, D.C. 20231

RECEIVED
JUN 28 2001
TECHNOLOGY CENTER 1700

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.


Japanese patent document No. 6-20927 has been discussed on page 4 of the subject specification and corresponds to U.S. Patent No. 5,164,974.

Applicants request that the above information be considered by the Examiner and that an initialed copy of the enclosed Form PTO-1449 be returned indicating that such

information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


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